

ABSTRACT

STAGE DEVICE FOR LASER PROCESSING MACHINE

In a stage device for a laser processing machine including a stage (12) which has lower portions thereof on opposite sides supported on linear guides (13) including slides (16) configured to move along a pair of guide rails (15) disposed in parallel with each other, and linear servomotors (14) which move the stage along the guide rails, a linear servomotor with a core is used as each of the linear servomotors, stators (17) of the linear servomotors are disposed at outer sides of the guide rails at a higher level than the guide rails while facing the stage, and movers (18) of the linear servomotors are disposed on opposite lateral side portions of the stage at such positions as to face the stage sides of the respective stators. In this way, it is possible to solve downward bend of the stage in the center due to its own weight, and also to reliably perform ultrafine processing using laser light.

Fig. 1